



1FW

Docket No.: M4065.0227/P227-A
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Tongbi Jiang et al.

Application No.: 09/998,165

Confirmation No.: 7636

Filed: December 3, 2001

Art Unit: 2829

For: METHOD AND APPARATUS FOR
REDUCING SUBSTRATE BIAS VOLTAGE
DROP

Examiner: E. T. Pert

STATUS INQUIRY

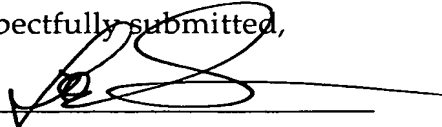
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

It is respectfully requested that the attorney named below be advised of the status of the above-identified application. Please advise us of when we might expect to receive an Office Action from the Patent and Trademark Office in response to the Amendment in Response to Non-Final Office Action filed January 20, 2006.

Dated: September 19, 2006

Respectfully submitted,

By 
Thomas J. D'Amico
Registration No.: 28,371
DICKSTEIN SHAPIRO MORIN &
OSHINSKY LLP
2101 L Street NW
Washington, DC 20037-1526
(202) 785-9700
Attorney for Applicant